



**BSI Standards Publication**

## **Semiconductor devices — Micro-electromechanical devices**

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Part 42: Measurement methods of electro-mechanical conversion  
characteristics of piezoelectric MEMS cantilever

## National foreword

This British Standard is the UK implementation of IEC 62047-42:2022.

The UK participation in its preparation was entrusted to Technical Committee EPL/47, Semiconductors.

A list of organizations represented on this committee can be obtained on request to its committee manager.

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### Amendments/corrigenda issued since publication

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